

Special Issue

Recent Advances in MEMS Mirrors

Message from the Guest Editors

MEMS mirror can manipulate light in chips and is a typical kind of optical MEMS actuators. MEMS mirror has been widely used in modulating the phase, amplitude and direction of light, and has gained tremendous commercial applications in the fields of autonomous driving, laser projection, optical communication and intelligent manufacturing. While achieving mass production applications, MEMS mirrors also face significant challenges. For example, in the application of autonomous driving LiDAR, In the field of space optical communication and consumer electronics. Therefore, this special issue seeks to showcase research papers, short communications, and review articles that focus on: (1) novel designs, fabrication, control, and modeling of MEMS mirrors Intended to enhance reliability, reduce costs, and improve closed-loop control accuracy; and (2) new applications of MEMS mirrors can be utilized in the fields of aerospace, aviation, industry, agriculture, and consumer electronics.

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